

Conventional Wafer Test Example

Figure 1A

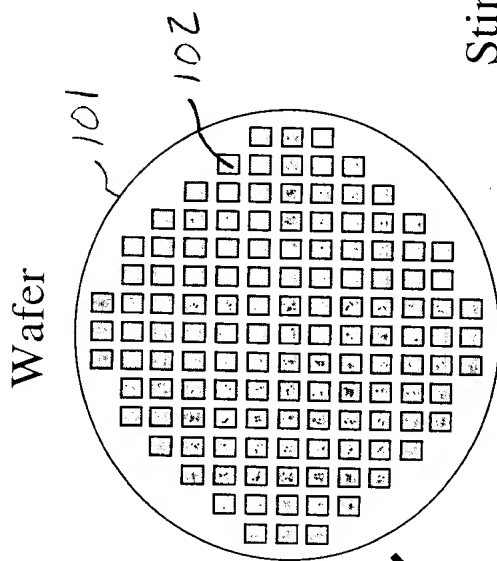


Figure 1B

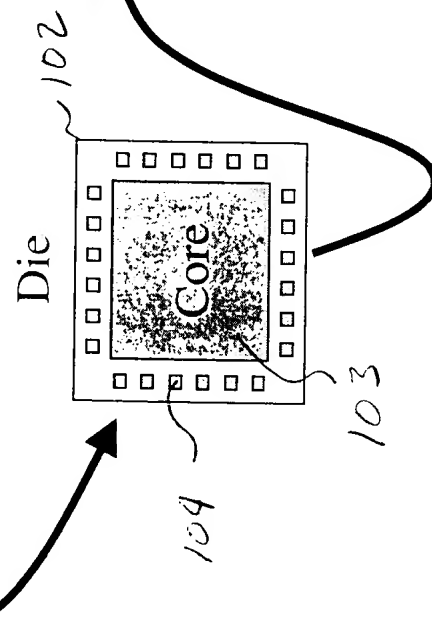
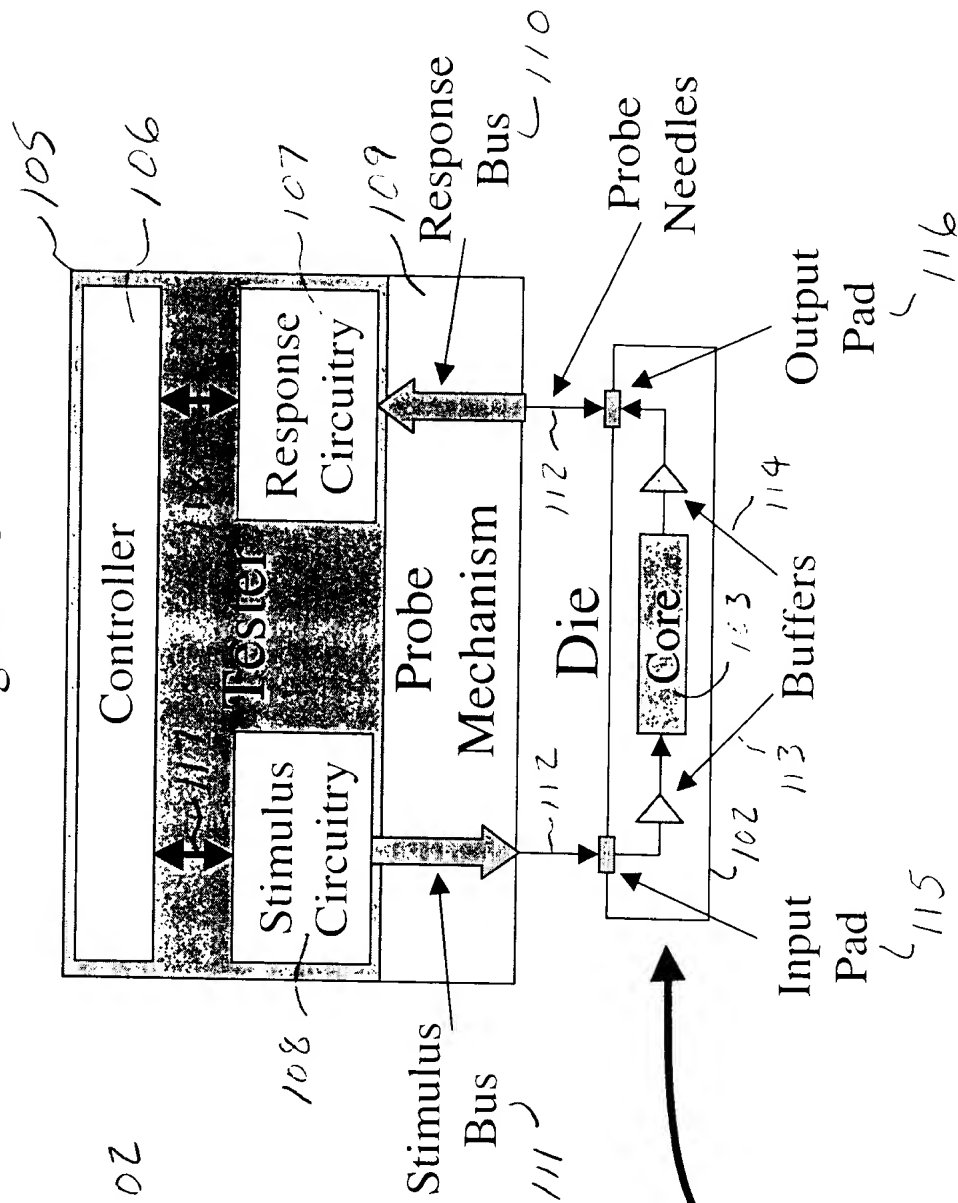
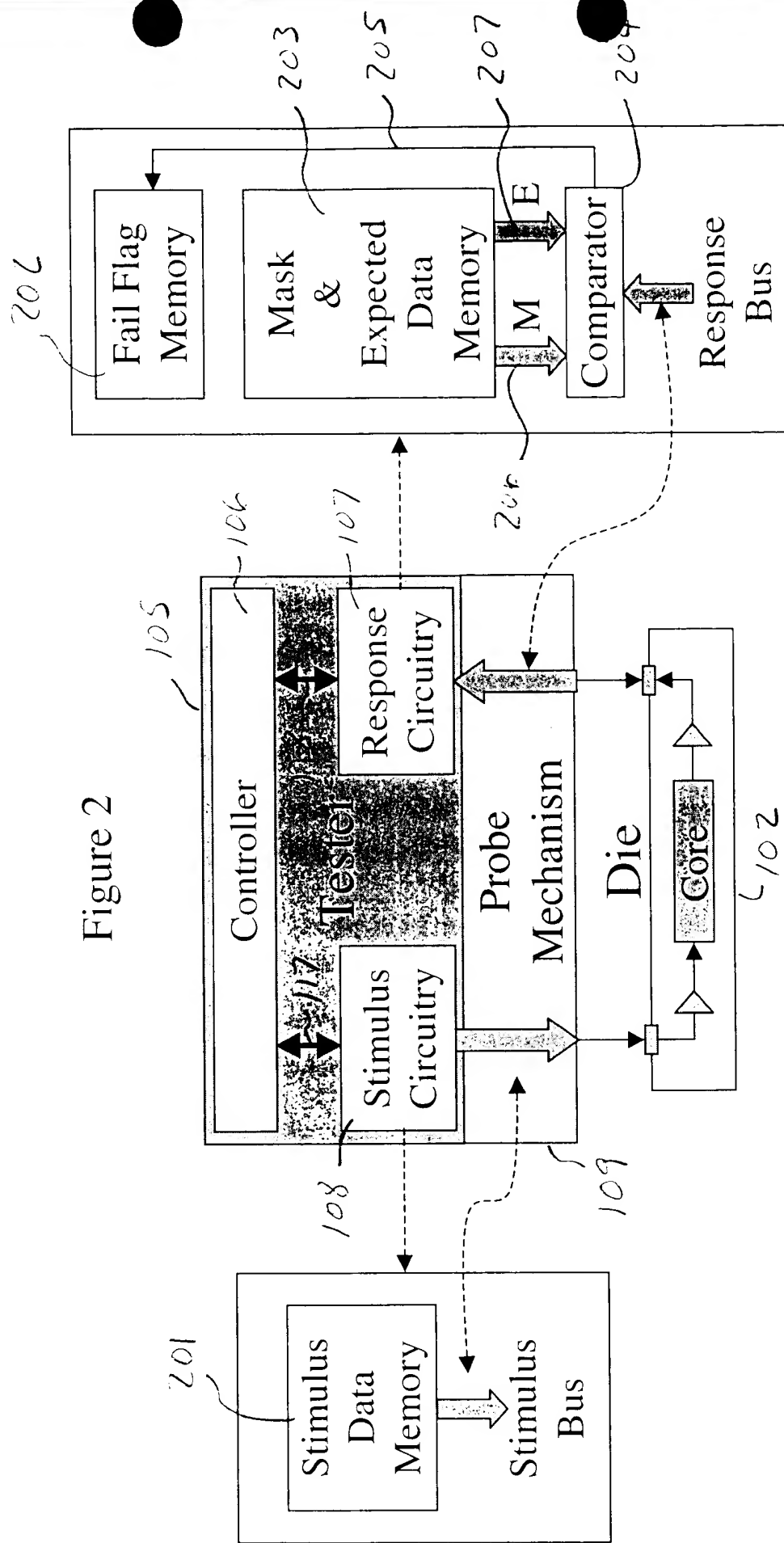


Figure 1C



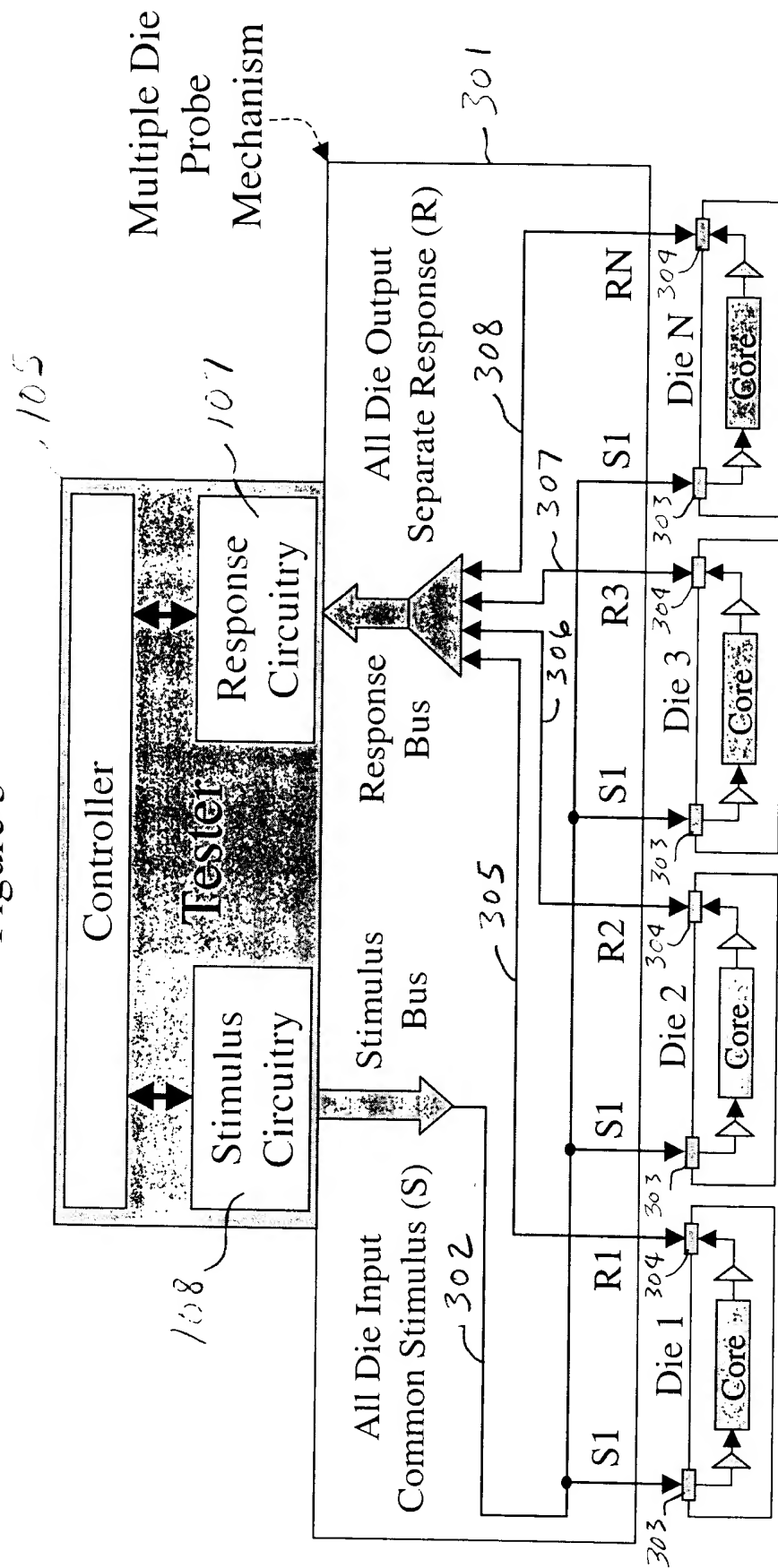
Conventional Tester Stimulus & Response Circuitry

Figure 2



Multiple Die Probe Test Example

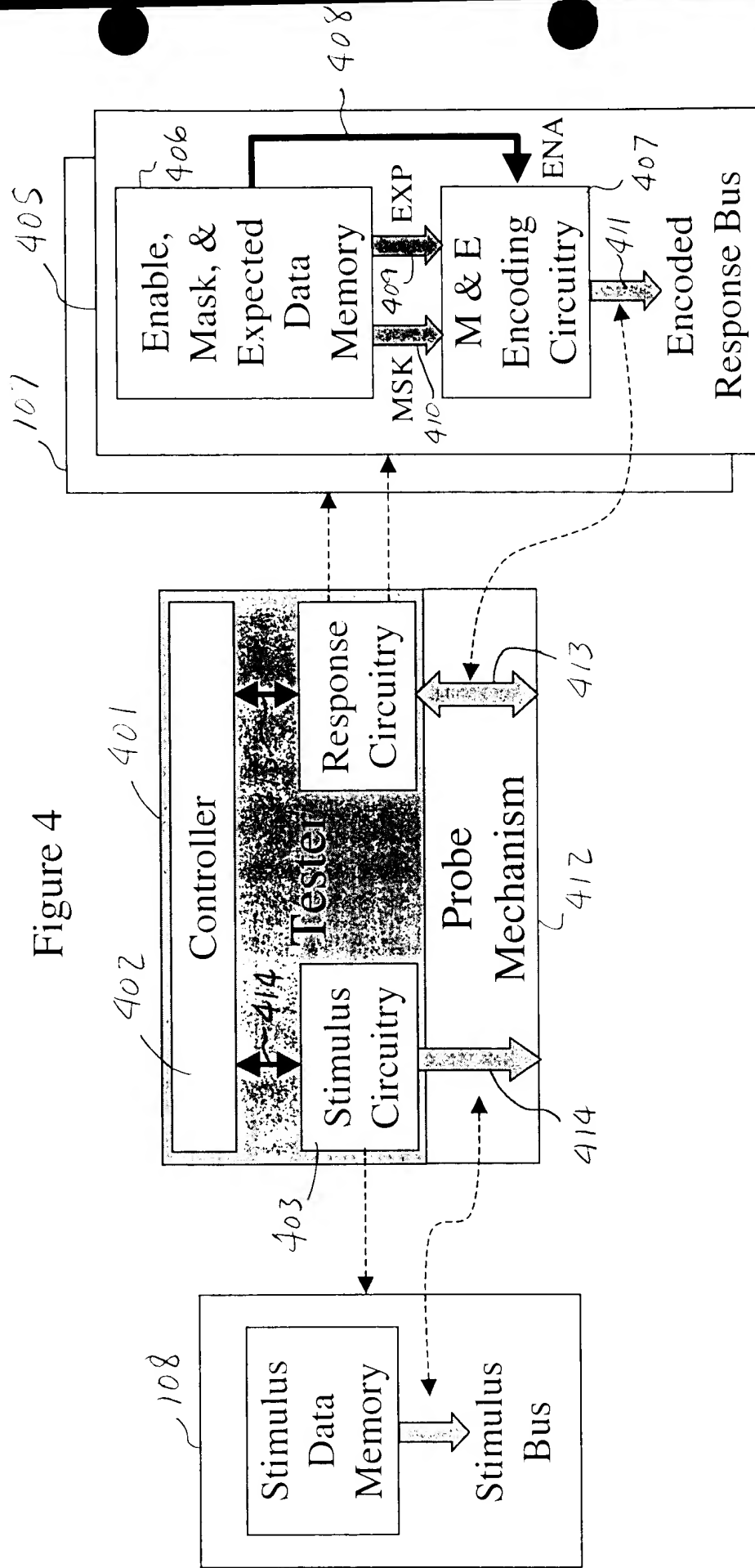
Figure 3



(Sum of R1-RN) <= (Tester Response Bus Width)

Adapting Testers To Support Improved Wafer Testing

Figure 4



Mask & Expected Encoding Circuitry

Figure 5A

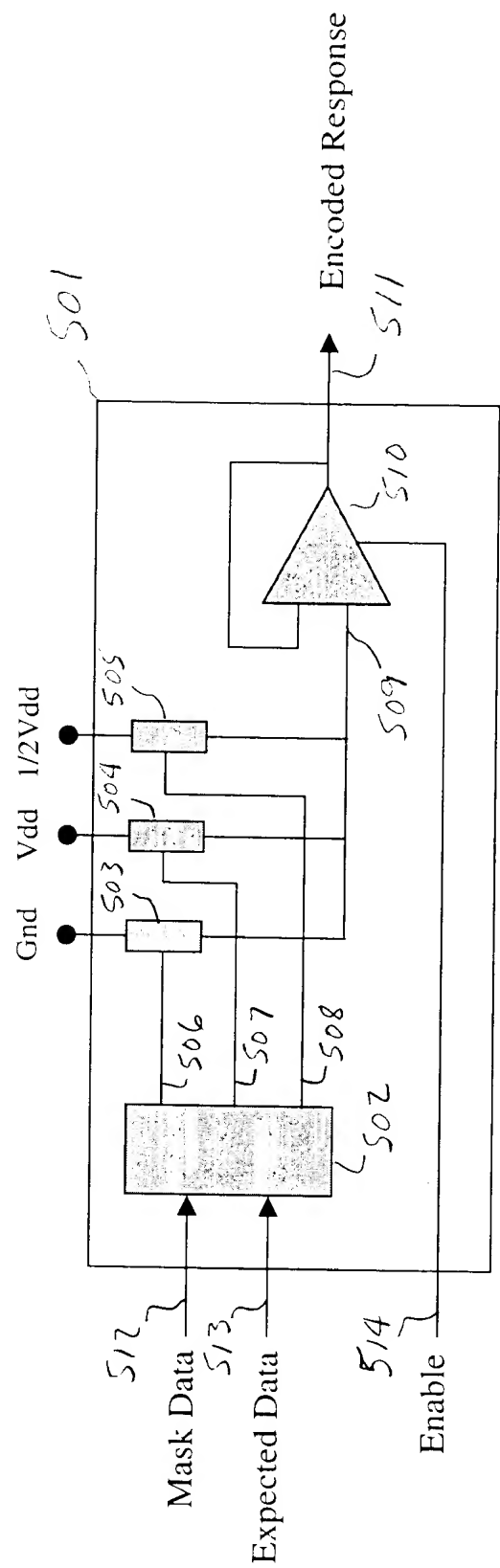
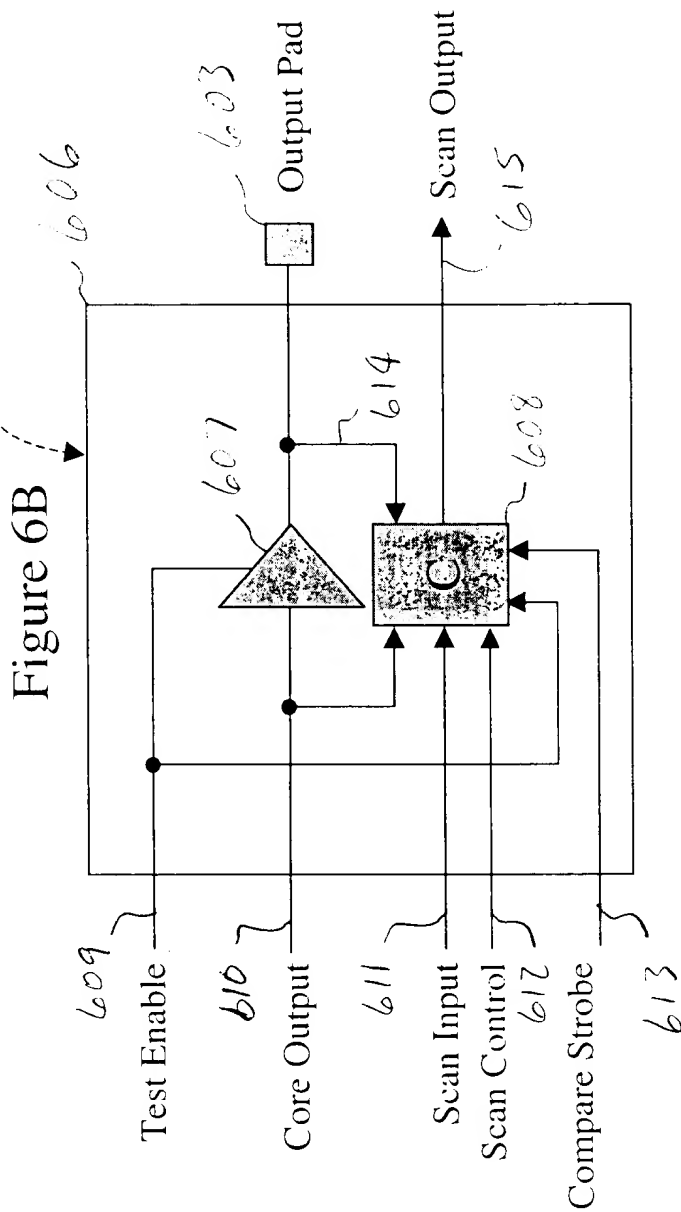
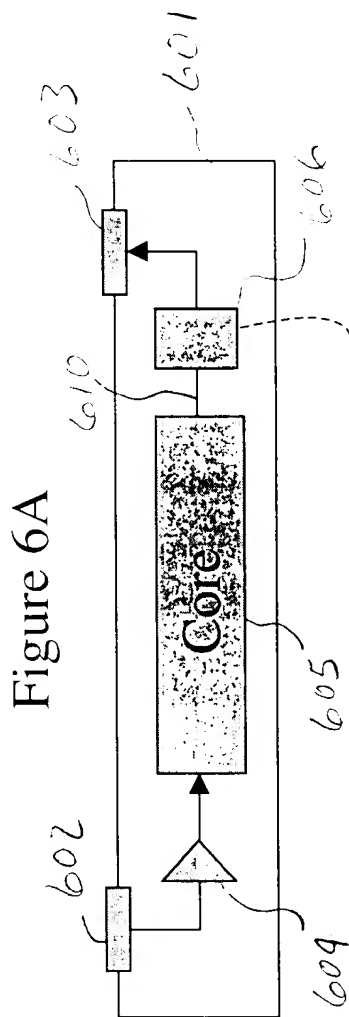


Figure 5B

ENA	MSK	EXP	ENR	Output Mode
0	0	0	Z	Disabled
1	0	0	Gnd	Low
1	0	1	Vdd	High
1	1	X	1/2Vdd	Mask

Adapting Die 2-State Outputs To Support Improved Wafer Testing



Maskable Comparator For 2-State Outputs

Figure 7A

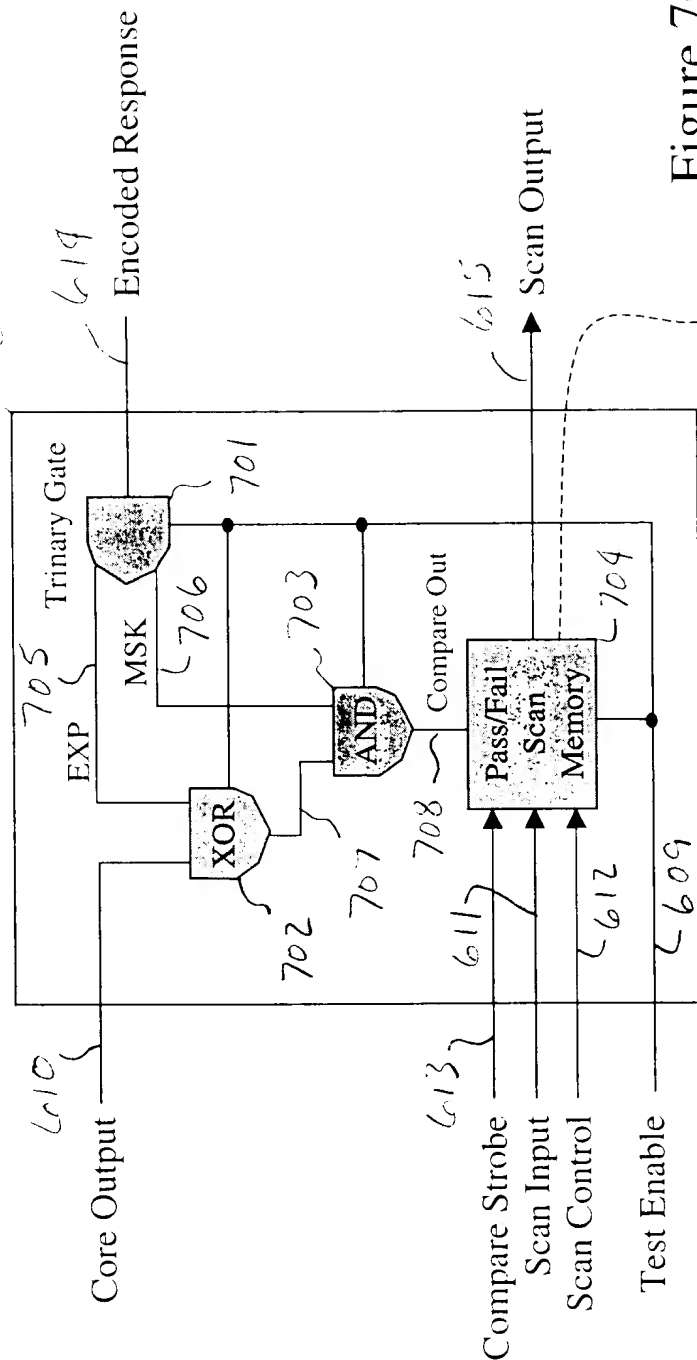


Figure 7C

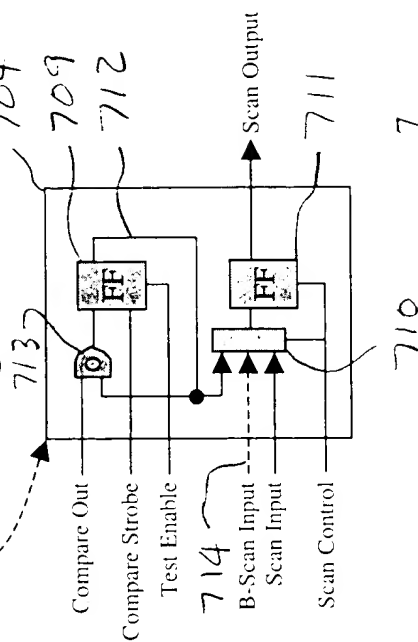


Figure 7B

TEN	ENR	MSK	EXP	Function Performed
0	X	X	X	Test Disabled
1	Gnd	1	0	Compare Low
1	Vdd	1	1	Compare High
1	1/2Vdd	0	X	Mask Compare

Figure 8A

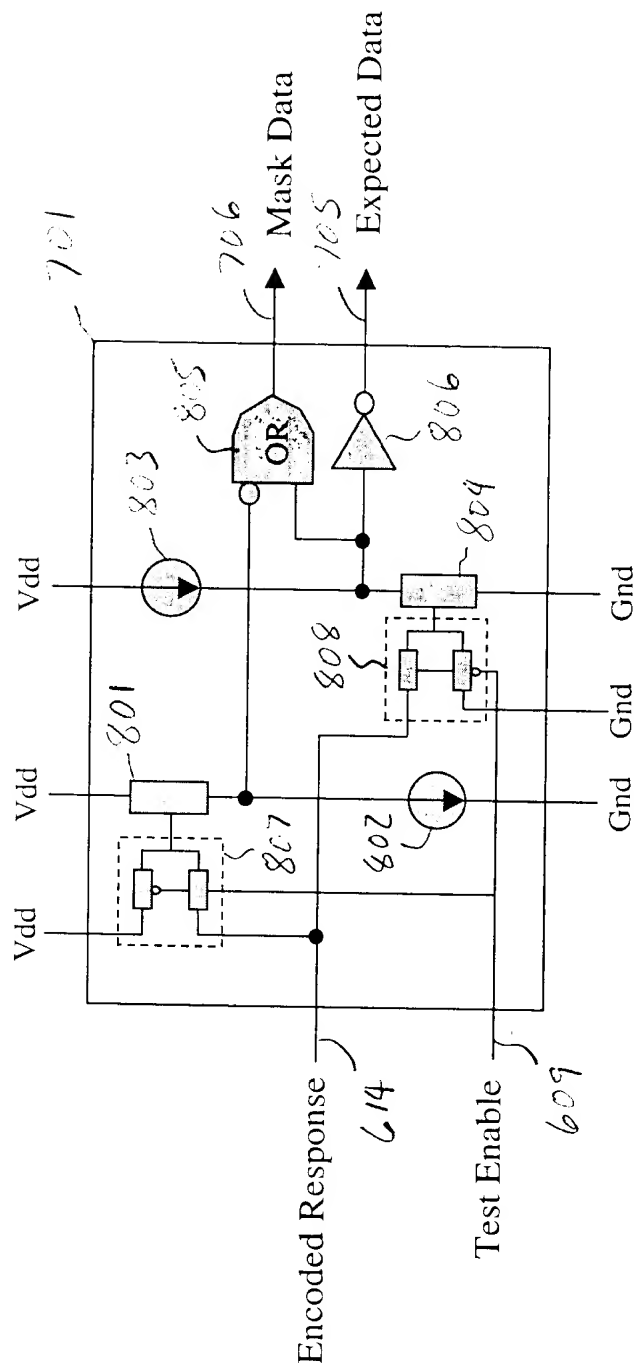
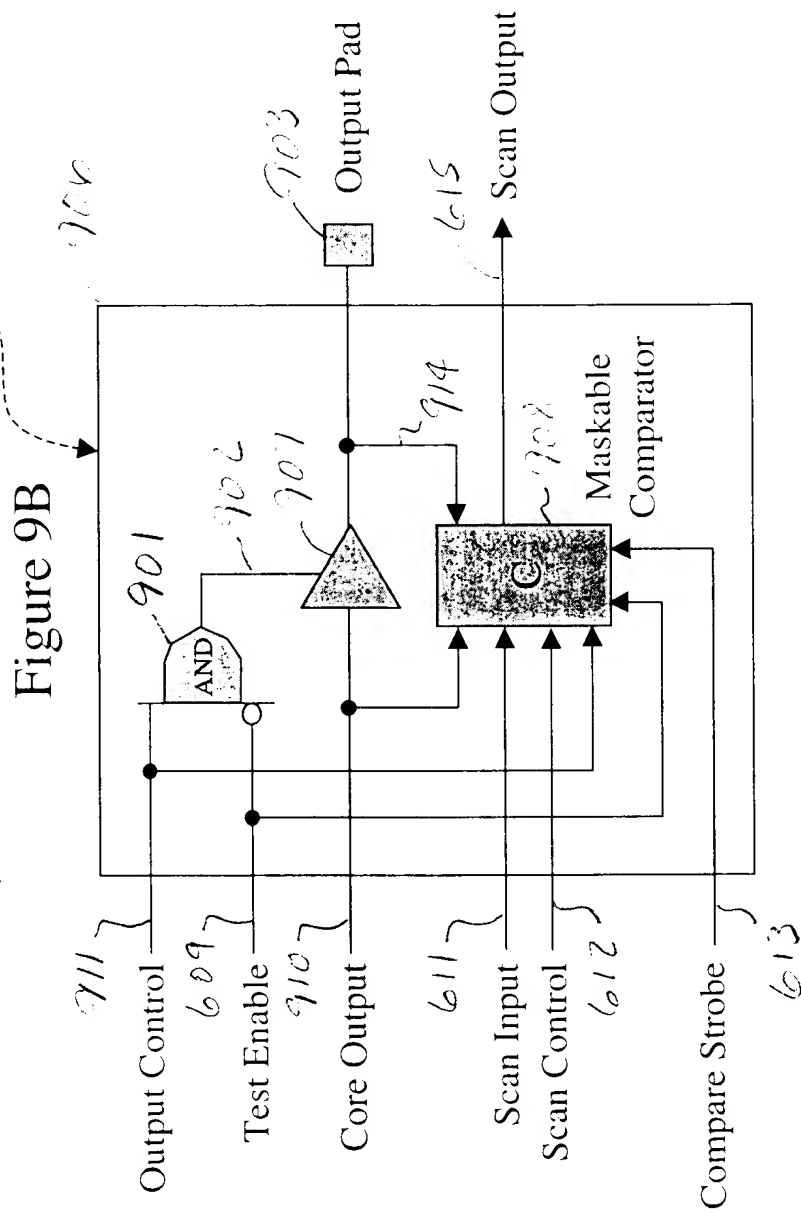
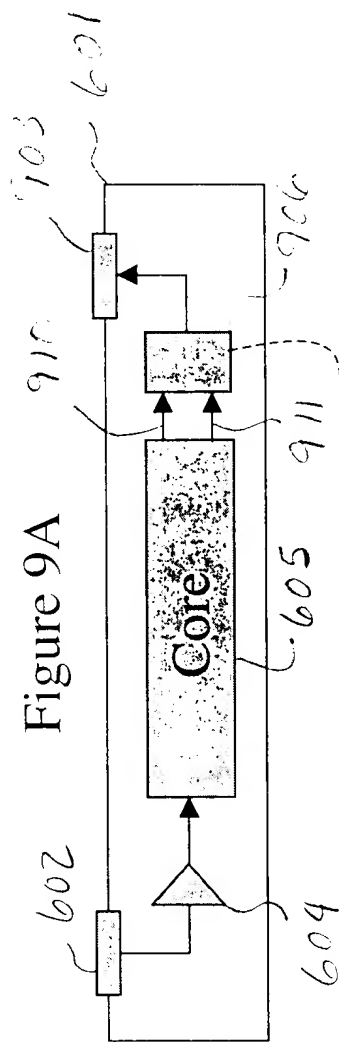


Figure 8B

TEN	ENR	MSK EXP	Function Performed
0	X	1 0	Gate Disabled
1	Gnd	1 0	Output a Low
1	Vdd	1 1	Output a High
1	1/2Vdd	0 X	Output a Mask

Adapting Die 3-State Outputs To Support Improved Wafer Testing



Maskable Comparator For 3-State Outputs

Figure 10A

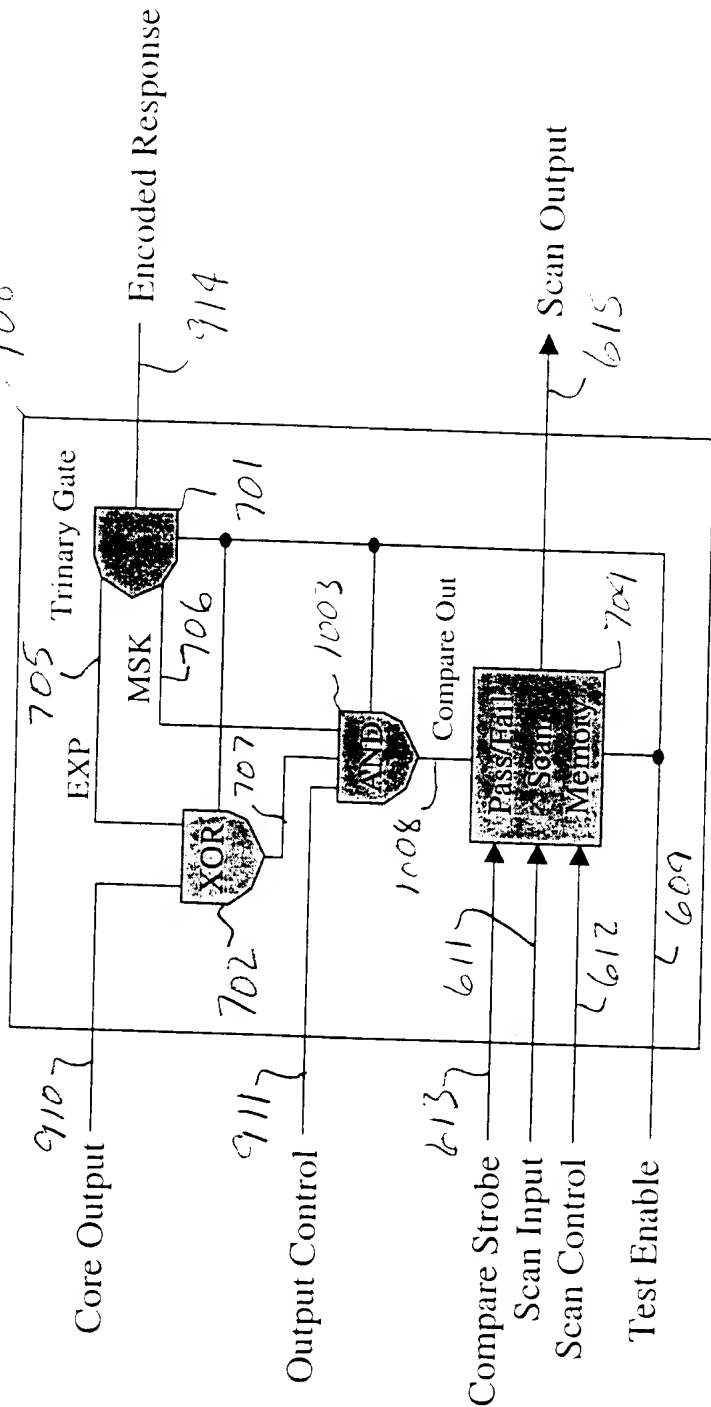


Figure 10B

OC	T _{EN}	ENR	MSK	EXP	Function Performed
X	0	X	X	X	Test Disabled
1	1	Gnd	1	0	Compare Low
1	1	Vdd	1	1	Compare High
1	1	1/2Vdd	0	X	Mask Compare
0	1	Gnd/Vdd	1	0/1	Test Output Control

110 111 110 111

109-60



2011



Maskable Comparator For Input/Outputs

Figure 12A

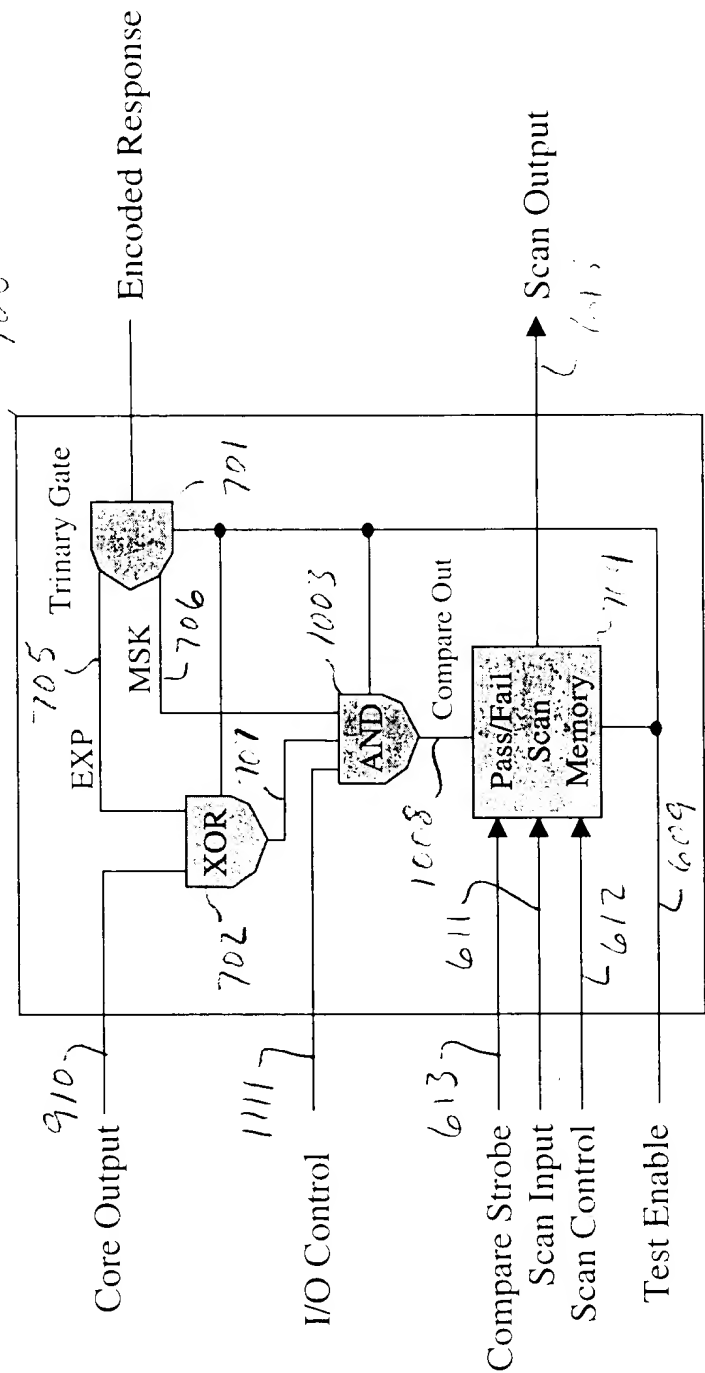
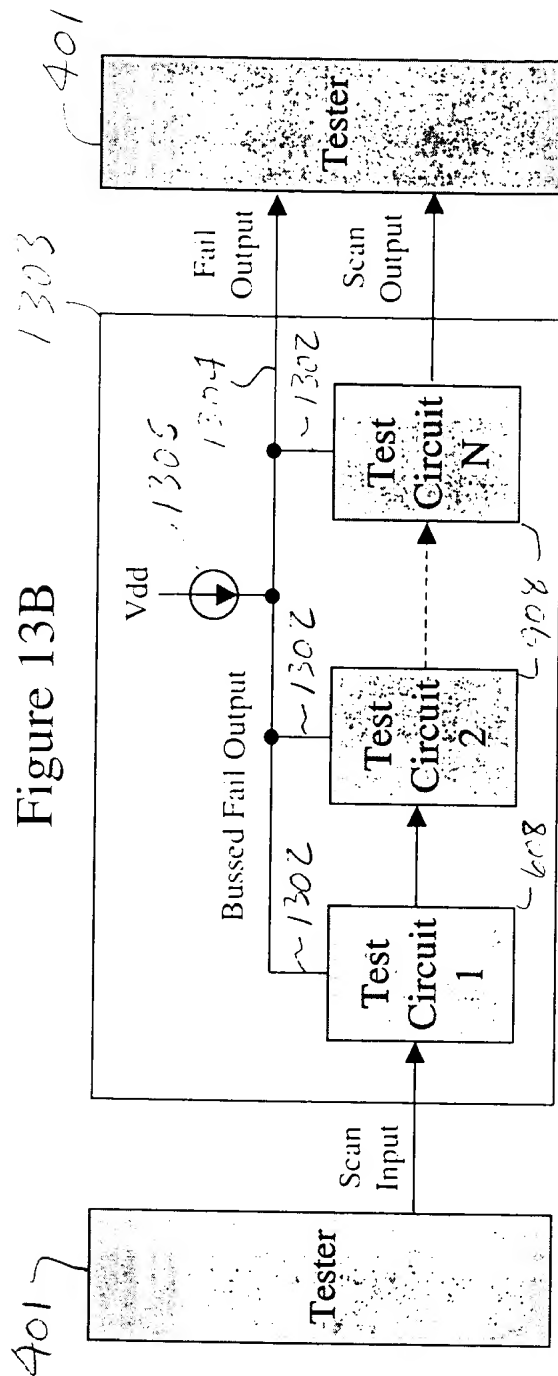
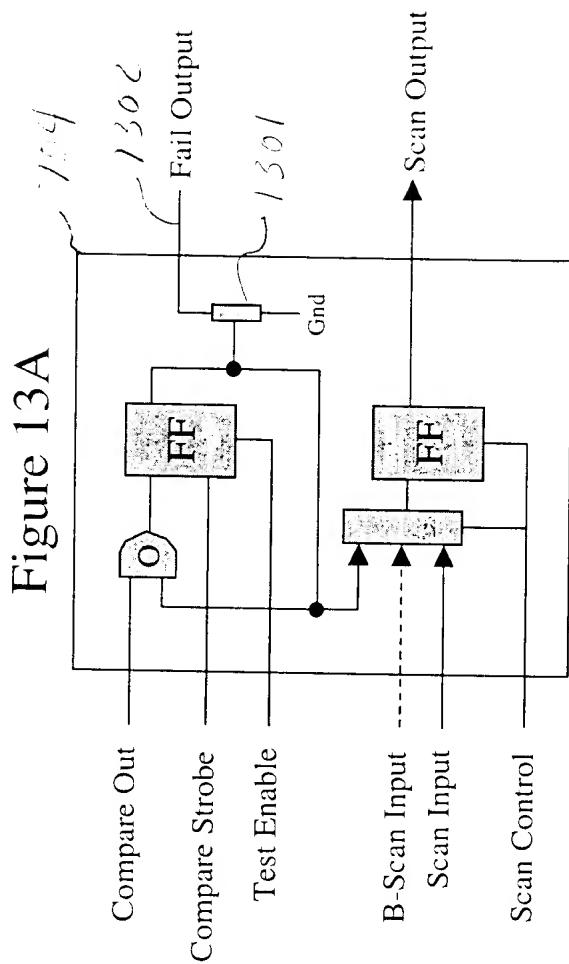


Figure 12B

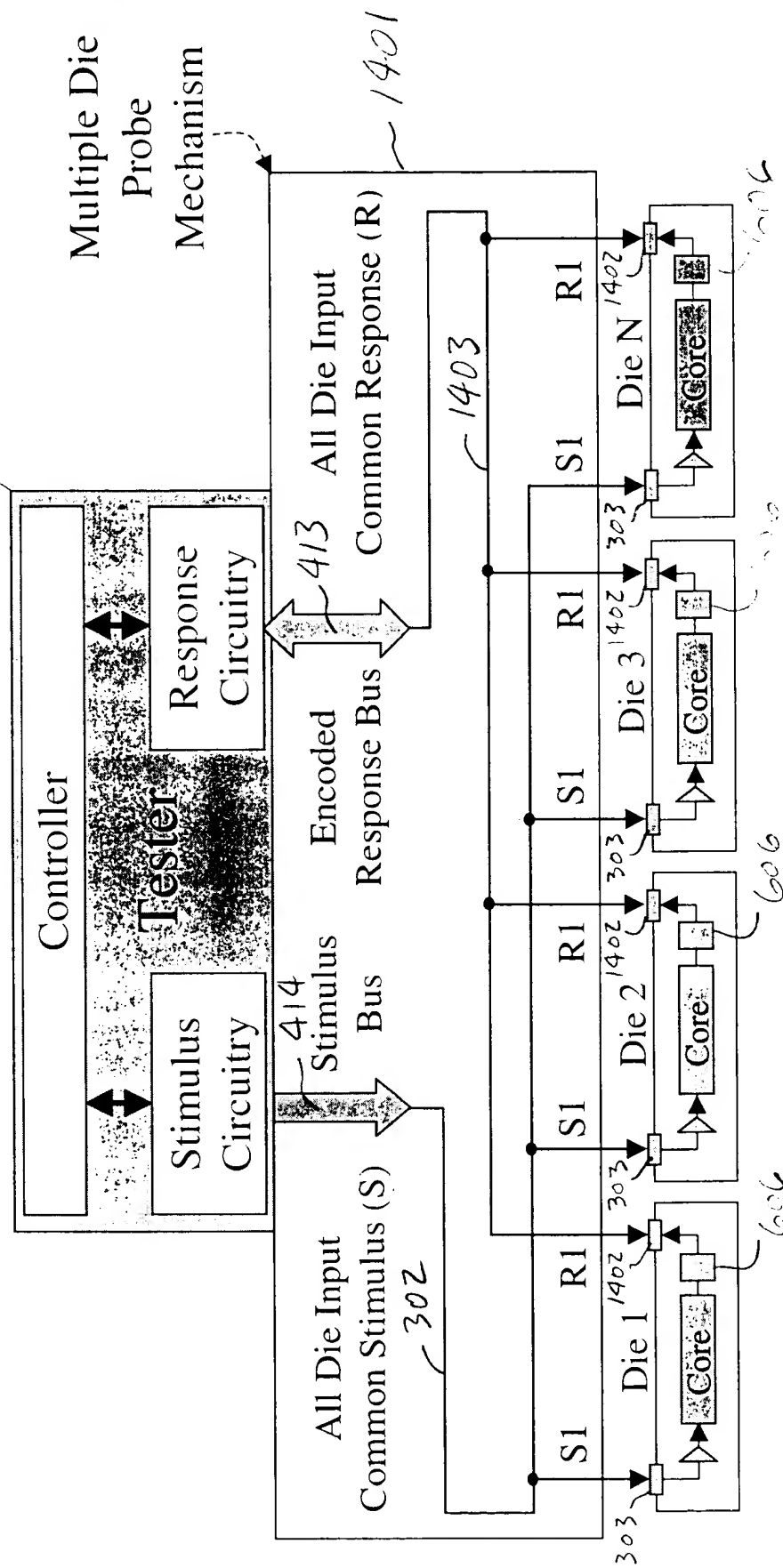
IOC	TEN	ENR	MSK	EXP	Function Performed
X	0	X	X	X	Test Disabled
1	1	Gnd	1	0	Compare Low
1	1	Vdd	1	1	Compare High
1	1	1/2Vdd	0	X	Mask Compare
0	1	Gnd/Vdd	1	0/1	Test I/O Control
0	1	Gnd/Vdd	1	0/1	Input Stimulus

Fail Output for Diagnostic Testing



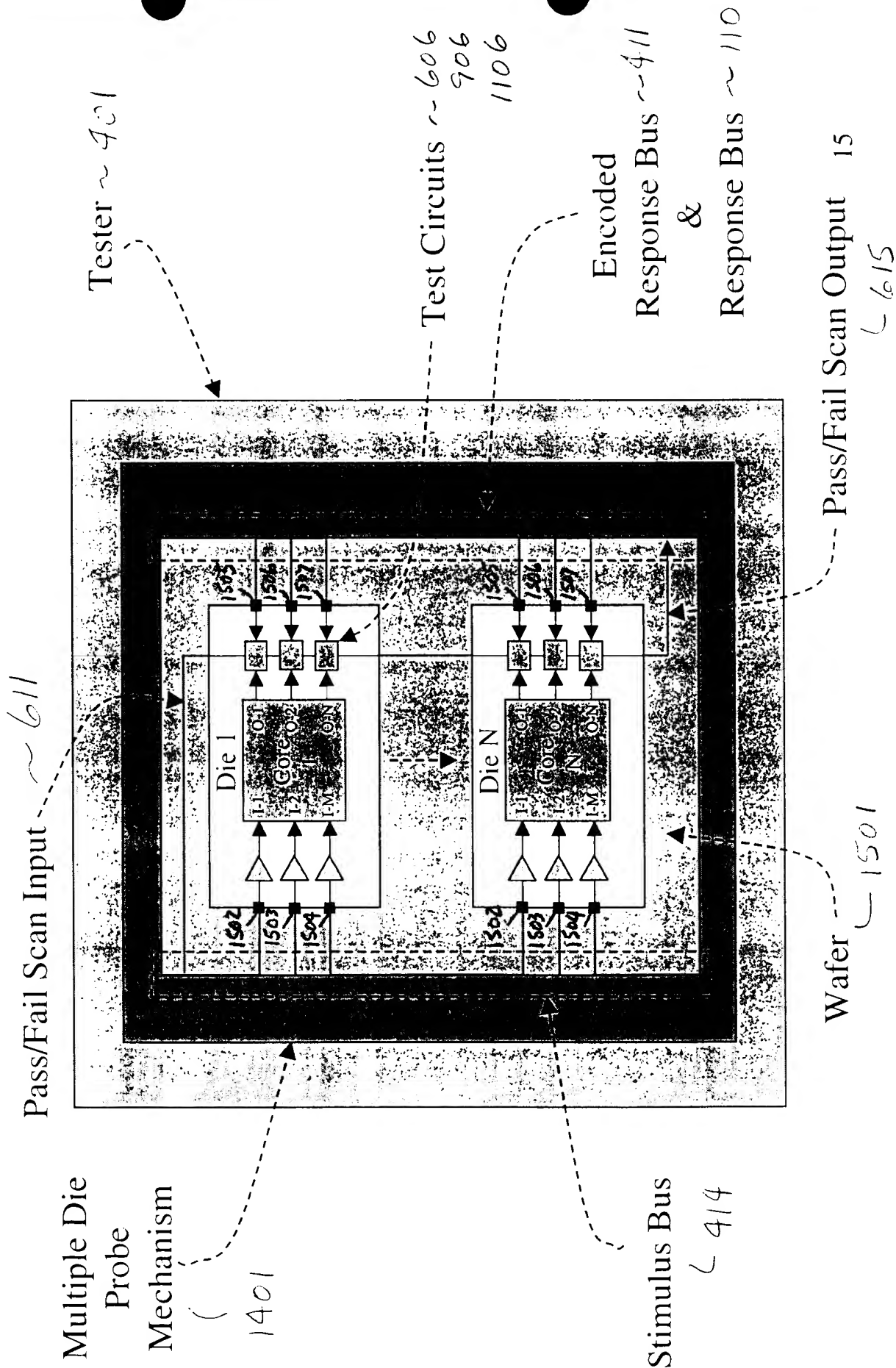
Improved Multiple Die Probe Test Example

Figure 14

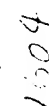


Conceptual View of Improved Die Test

Figure 15

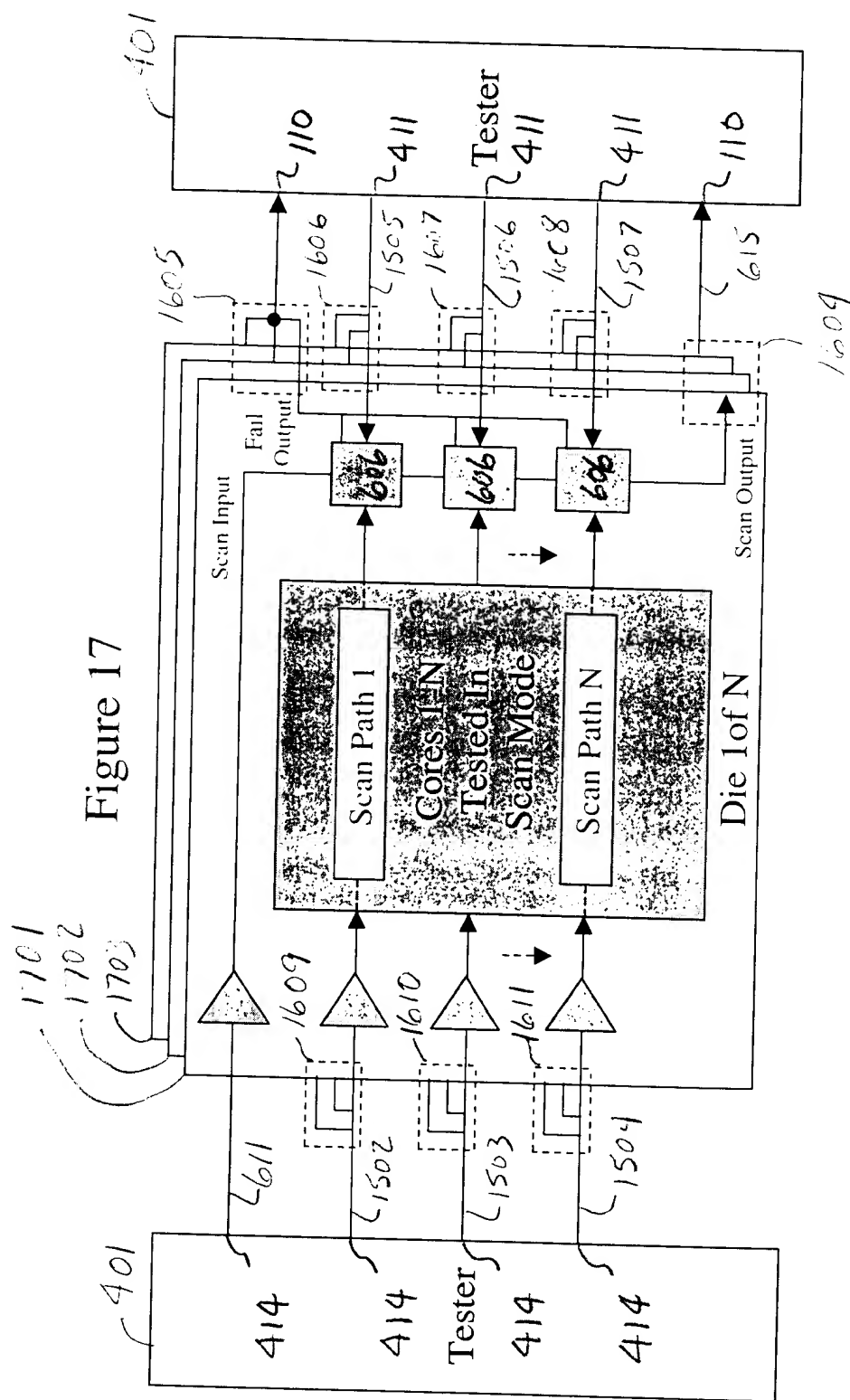


1601
1602
1603



Die Being Tested in Scan Mode

Figure 17



Testing System-On-Chip Die having Multiple Embedded IP Core Sub-Circuits

Figure 18A

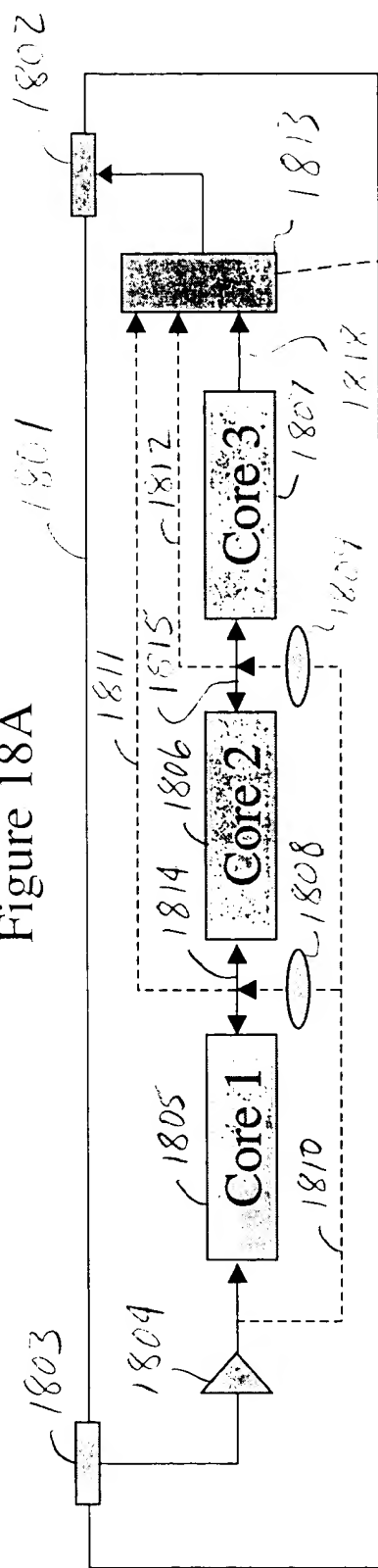
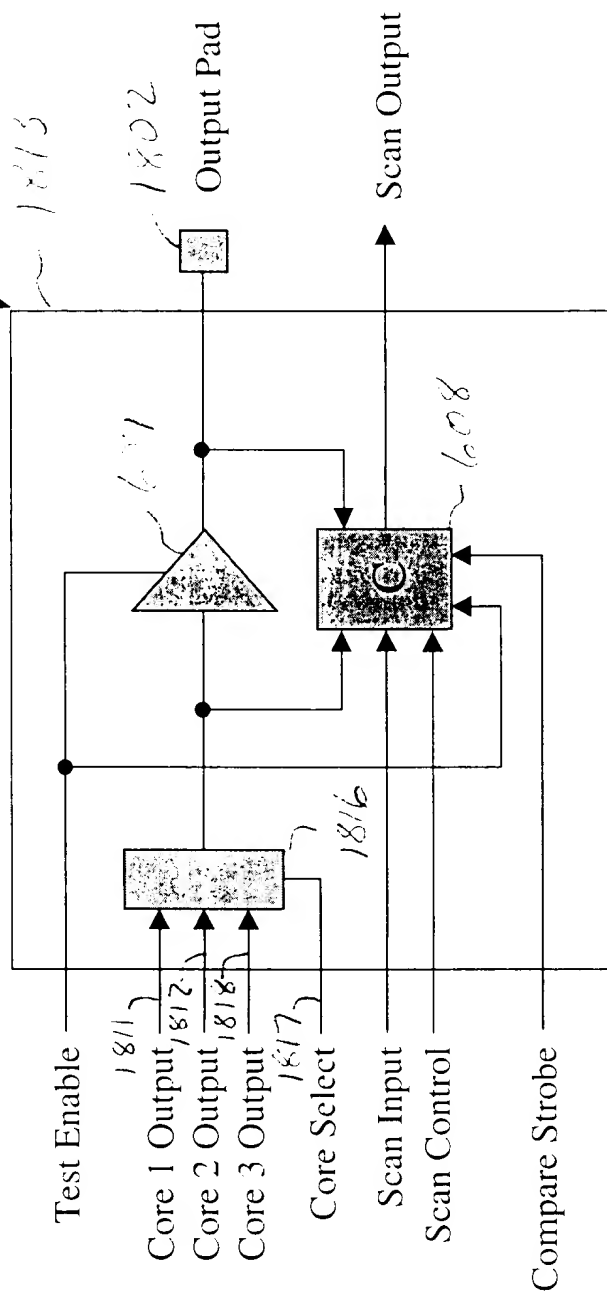
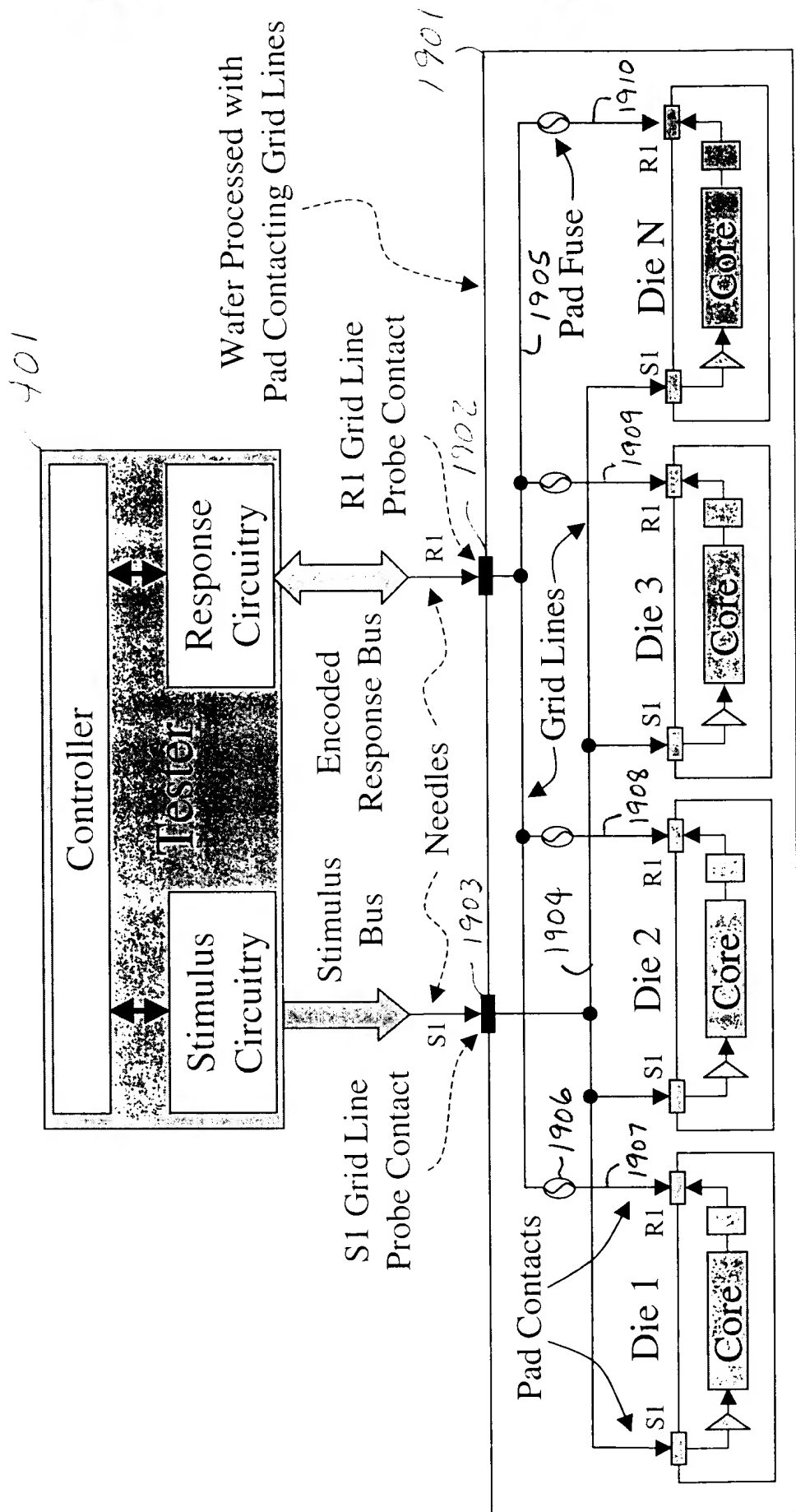


Figure 18B



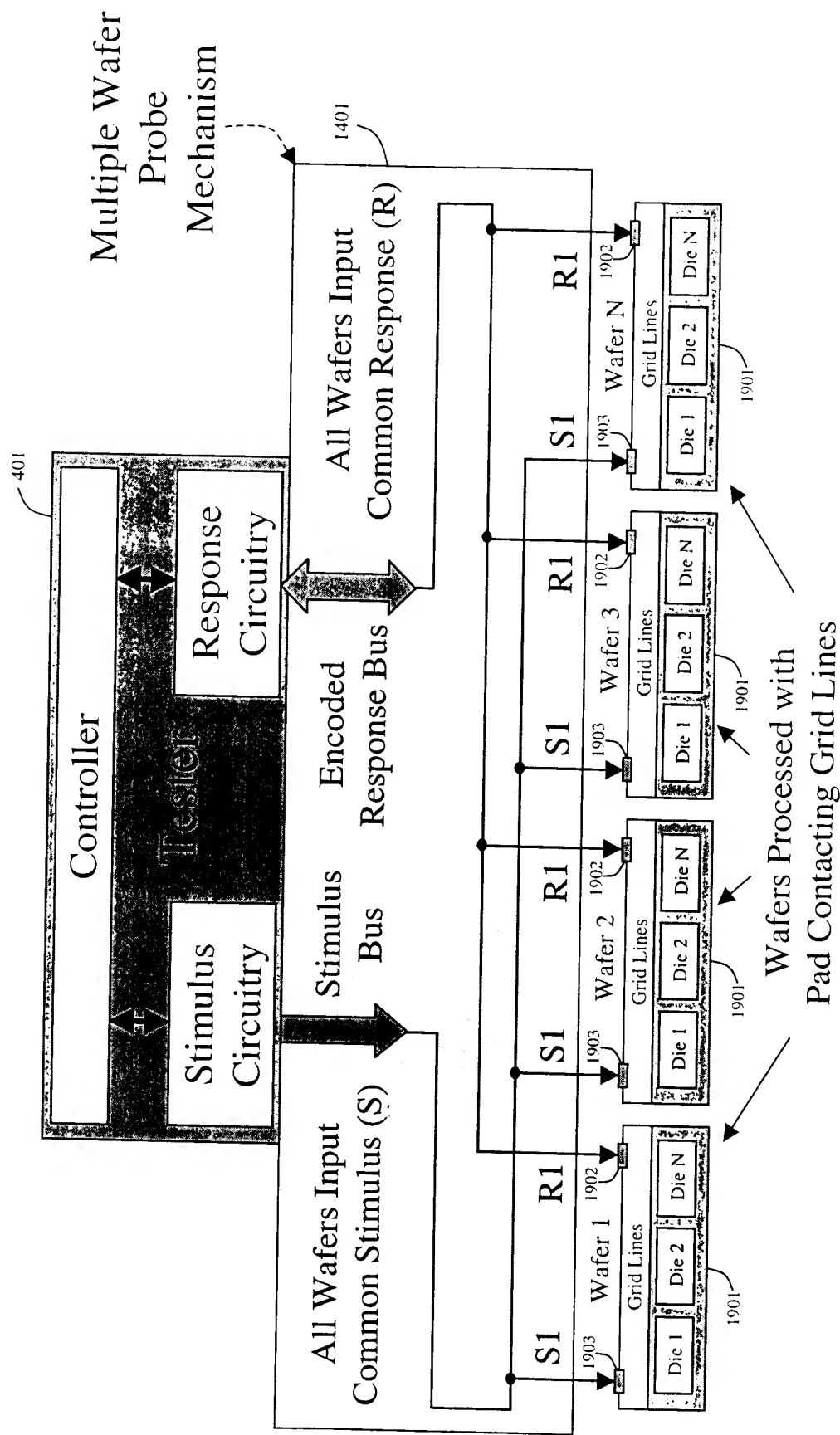
Adapting Wafers To Support Improved Wafer Testing

Figure 19



Improved Multiple Wafer Test Example

Figure 19A



Improved Multiple IC Test Example

Figure 20

